

TRADEMARK ASSIGNMENT COVER SHEET

Electronic Version v1.1
Stylesheet Version v1.2

ETAS ID: TM767907

SUBMISSION TYPE:	NEW ASSIGNMENT		
NATURE OF CONVEYANCE:	RELEASE OF SECURITY INTEREST		
CONVEYING PARTY DATA			
Name	Formerly	Execution Date	Entity Type
EASTWARD FUND MANAGEMENT, LLC		11/14/2022	Limited Liability Company: DELAWARE
RECEIVING PARTY DATA			
Name:	MOVELLA INC.		
Street Address:	2570 N. 1st St., Suite 300		
City:	San Jose		
State/Country:	CALIFORNIA		
Postal Code:	95131		
Entity Type:	Corporation: DELAWARE		
PROPERTY NUMBERS Total: 4			
Property Type	Number	Word Mark	
Serial Number:	88491567	SENSFIT	
Registration Number:	4700413	MCUBE	
Registration Number:	4254341	MCUBE	
Registration Number:	4659788	MCUBE	
CORRESPONDENCE DATA			
Fax Number:			
	<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i>		
Phone:	4159831234		
Email:	sdipdocket@pillsburylaw.com		
Correspondent Name:	Sam E. Iverson		
Address Line 1:	Four Embarcadero Center, 22nd Floor		
Address Line 4:	San Francisco, CALIFORNIA 94111-5998		
NAME OF SUBMITTER:	Sam E. Iverson		
SIGNATURE:	/Sam E. Iverson/		
DATE SIGNED:	11/15/2022		
Total Attachments: 14			
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page1.tif			
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page2.tif			

CH \$115.00 88491567

source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page3.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page4.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page5.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page6.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page7.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page8.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page9.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page10.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page11.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page12.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page13.tif
source=Eastward - Movella - IP Release Fac 1 [Executed Copy]#page14.tif

RELEASE OF SECURITY INTEREST

This Release of Security Interest is made as of November 14, 2022, by Eastward Fund Management, LLC, a Delaware limited liability company (“Lender”), in favor of Movella Inc., a Delaware corporation (“Company”), (formerly/as successor-in-interest by assignment to) mCube, Inc., with its principal place of business located at 2570 N. 1st St., Suite 300, San Jose, CA 95131.

Recitals

WHEREAS under that certain Intellectual Property Security Agreement dated as of June 8, 2020 (the “Security Agreement”), Company granted to Lender a security interest in all of the Company’s right, title and interest in and to the intellectual property of Company, including without limitation, the Intellectual Property Collateral (as that term is defined in the Security Agreement, including all items of intellectual property and related rights listed in the Security Agreement), and specifically the patent and trademark items listed on Exhibits B and C attached hereto, which was recorded with the US Patent and Trademark Office on September 2, 2020 at Reel Number 053826, Frame Number 0626 and at Reel Number 7044, Frame Number 0014, respectively (all such intellectual property collectively, the “Intellectual Property”).

WHEREAS Company has no outstanding obligations to Lender, Lender agrees to release and relinquish and does hereby release and relinquish its security interest in the Intellectual Property.

Agreement

NOW THEREFORE, Lender hereby terminates and agrees that the Security Agreement is terminated and Lender terminates, relinquishes and releases its security interest in the Intellectual Property and reassigns to Company, without warranty or recourse, all interest of Lender in the Intellectual Property. Lender further agrees to execute and deliver to Company any and all further documents or instruments and do any and all further acts which Company reasonably requests in order to confirm this release and Company's right, title and interest in and to the Intellectual Property.

LENDER:

Eas^{tward Fund Management} LLC
DocuSigned by:

By: Dennis P. Cameron
D6CA308B965D4A9...

Name: Dennis Cameron

Title: Chief Executive Officer

EXHIBIT B

Patents

No.	Description	Registration/ Application Number	Registration/ Application Date
1.	Three Axis Magnetic Sensor Device and Method	8,742,520	06/03/2014
2.	Method and Structure of Integrated Micro Electro-Mechanical Systems and Electronic Devices Using Edge Bond Pads	8,592,993	11/26/2013
3.	Method and Structure of Sensors or Electronic Devices Using Vertical Mounting	8,749,004	06/10/2014
4.	Method and Structure of Sensors and MEMS Devices Using Vertical Mounting with Interconnections	8,981,560	(03/17/2015
5.	Low Power Rotational Detection Methods and Apparatus	16/101,276	08/10/2018
6.	MEMS Device with Stiction Recover and Methods	15/877,999	01/23/2018
7.	Differential MEMS Device and Methods	16/530,923	(08/02/2019

No.	Description	Registration/ Application Number	Registration/ Application Date
8.	Portable Computing Device and Methods	16/655,124	10/16/2019
9.	Flexible Sensor System and Methods	16/734,234	1/4/2019
10.	Device and Method for Using Time Rate of Change of Sensor Data to Determine Device Rotation	10,197,587	02/05/2019
11.	Dynamic Offset Correction for Calibration of MEMS Sensor	10,324,108	06/18/2019
12.	Three Axis Magnetic Sensor Device and Method	8,486,723	07/16/2013
13.	Accurate Gyroscope Device Using MEMS and Quartz	8,584,521	11/19/2013
14.	Touchscreen Operation Threshold Methods and Apparatus	8,643,612	02/04/2014
15.	Analog Touchscreen Methods and Apparatus	8,797,279	08/05/2014

No.	Description	Registration/ Application Number	Registration/ Application Date
16.	MEMS-Based Dual and Single Proof-Mass Accelerometer Methods and Apparatus	9,246,017	01/26/2016
17.	Selective Accelerometer Data Processing Methods and Apparatus	9,335,845	05/10/2016
18.	Security System and Methods for Integrated Devices	9,418,247	08/16/2016
19.	Three Axis Magnetic Sensor Device and Method Using Flex Cables	9,423,473	08/23/2016
20.	Method of Reducing Gyroscope Oscillator Start-Up Time and Device Therefor	9,464,899	10/11/2016
21.	Method and Device for Magnetoresistive Sensor	9,588,194	03/07/2017
22.	Method and Structure of Three Dimensional CMOS Transistors with Hybrid Crystal Orientations	9,595,479	03/14/2017
23.	Method and Device for Calibrating a Magnetometer Using Partial Sampling	9,677,906	06/13/2017

No.	Description	Registration/ Application Number	Registration/ Application Date
24.	Dual Accelerometer Plus Magnetometer Body Rotation Rate Sensor-Gyrometer	13/758,381	02/04/2013
25.	Method of Fabricating MEMS Devices Using Plasma Etching and Device Thereof	14/658,114	03/13/2015
26.	Security System and Methods for Integrated Devices	10,078,112	09/18/2018
27.	Multi-Layer Single Chip MEMS WLCSP Fabrication	10,106,399	10/23/2018
28.	Method and Apparatus for Real-Time Motion Direction Detection via Acceleration-Magnetic Fusion	10,175,778	01/08/2019
29.	MEMS Device with Reduced Dynamic Stress and Methods	10,322,926	06/18/2019
30.	Umbrella, Umbrella Peripheral and Methods	10,561,210	02/18/2020
31.	Multiple MEMS Device and Methods	10,605,823	03/31/2020

No.	Description	Registration/ Application Number	Registration/ Application Date
32.	Method and Apparatus for Patterning Micro and Nano Structures Using a Mask-Less Process	7,473,912	01/06/2009
33.	Method and Structure for an Out-of-Plane Compliant Micro Actuator	7,498,715	03/03/2009
34.	Method and Structure for Kinetic Energy Based Generator for Portable Electronic Devices	7,608,933	10/27/2009
35.	Method and Structure for an Out-of-Plane Compliant Micro Actuator	7,928,632	04/19/2011
36.	Method and Structure of Monolithically Integrated IC-MEMS Oscillator Using IC Foundry-Compatible Processes	8,071,398	12/06/2011
37.	Method and Structure of Monolithically Integrated Infrared Sensing Device	8,120,076	02/21/2012
38.	Method and Structures of Monolithically Integrated ESD Suppression Device	8,148,781	04/03/2012
39.	Methods and Apparatus for Facilitating Capture of Magnetic Credit Card Data on a Hand Held Device	8,181,874	05/22/2012

No.	Description	Registration/ Application Number	Registration/ Application Date
40.	Method and Structure of Monolithically Integrated Inertial Sensor Using IC Foundry-Compatible Process	8,227,285	07/24/2012
41.	Method and Structure of Wafer Level Encapsulation of Integrated Circuits with Cavity	8,227,911	07/24/2012
42.	Foundry Compatible Process for Manufacturing a Magneto Meter Using Lorentz Force for Integrated Systems	8,236,577	08/07/2012
43.	Methods and Apparatus for Capturing Magnetic Credit Card Data on a Hand Held Device	8,245,923	08/21/2012
44.	Method and Structure of an Integrated CMOS and MEMS Device Using Air Dielectric	8,324,047	12/04/2012
45.	Method and Structure of Integrated Micro Electro-Mechanical Systems and Electronic Devices Using Edge Bond Pads	8,367,522	02/05/2013
46.	Integrated MEMS and CMOS Package and Method	8,395,252	03/12/2013

No.	Description	Registration/ Application Number	Registration/ Application Date
47.	Magneto Meter Using Lorentz Force for Integrated Systems	8,402,666	03/26/2013
48.	Multiple Magneto Meters Using Lorentz Force for Integrated Systems	8,407,905	04/02/2013
49.	Integrated CMOS and MEMS with Air Dielectric Method and System	8,421,082	04/16/2013
50.	Method and Structure of Monolithically Integrated Inertial Sensor Using IC Foundry-Compatible Processes	8,432,005	04/30/2013
51.	Method and Structure of Sensors or Electronic Devices Using Vertical Mounting	8,476,084	07/02/2013
52.	Method and Structure of Sensors and MEMS Devices Using Vertical Mounting with Interconnections	8,476,129	07/02/2013
53.	Method and Structure of Monolithically Integrated Microneedle Biochip	8,506,529	08/13/2013
54.	Anchor Design and Method for MEMS Transducer Apparatuses	8,553,389	10/08/2013

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
55.	Package Tolerate Design and Method	8,564,075	10/22/2013
56.	Method and Structure of Wafer Level Encapsulation of Integrated Circuits with Cavity	8,569,180	10/29/2013
57.	Multi-Axis Integrated MEMS Devices with CMOS Circuits and Method Therefor	8,637,943	01/28/2014
58.	Methods and Structure for Adapting MEMS Structures to Form Electrical Interconnections for Integrated Circuits	8,652,961	02/18/2014
59.	Method and Structure of Monolithically Integrated IC-MEMS Oscillator Using IC Foundry-Compatible Processes	8,704,238	04/22/2014
60.	Method and Structure for Adding Mass with Stress Isolation to MEMS Structures	8,710,597	04/29/2014
61.	Methods and Apparatus for Initiating Image Capture on a Hand-Held Device	8,723,986	05/13/2014
62.	Integrated Inertial Sensing Apparatus Using MEMS and Quartz Configured on Crystallographic Planes	8,794,065	08/05/2014

No.	Description	Registration/ Application Number	Registration/ Application Date
63.	Method and Structure of Monolithically Integrated Pressure Sensor Using IC Foundry-Compatible Processes	8,796,746	08/05/2014
64.	Method and Structure of Monolithically Integrated Micromachined Microphone Using IC Foundry-Compatible Processes	8,796,790	08/05/2014
65.	Integrated System on Chip Using Multiple MEMS and CMOS Devices	8,823,007	09/02/2014
66.	Methods and Apparatus for Object Tracking on a Hand-Held Device	8,928,602	01/06/2015
67.	Methods and Apparatus for Operating Hysteresis on a Hand Held Device	8,928,696	01/06/2015
68.	Integrated RF MEMS, Control Systems and Methods	8,936,959	01/20/2015
69.	Three Axis Magnetic Sensor Device and Method Using Flex Cables	8,969,101	03/03/2015

No.	Description	Registration/ Application Number	Registration/ Application Date
70.	Oxide Retainer Method for MEMS Devices	8,993,362	03/31/2015
71.	Method and Structure of Monolithically Integrated ESD Suppression Device	8,999,835	04/07/2015
72.	Multi-Axis Integrated MEMS Devices with CMOS Circuits and Methods Therefor	9,150,406	10/06/2015
73.	Distributed MEMS Devices Time Synchronization Methods and System	9,174,838	11/03/2015
74.	Substrate Curvature Compensation Methods and Apparatus	9,291,638	03/22/2016
75.	Method and Structure for Adding Mass with Stress Isolation to MEMS Structures	9,321,629	04/26/2016
76.	Method and Structure of Monolithically Integrated Absolute Pressure Sensor	9,340,414	05/17/2016
77.	Integrated CMOS and MEMS Devices with Air Dielectrics	9,365,412	06/14/2016

No.	Description	Registration/ Application Number	Registration/ Application Date
78.	Method for Fabricating a Transducer Apparatus	9,376,312	06/28/2016
79.	System on a Chip Using Integrated MEMS and CMOS Devices	9,440,846	09/13/2016
80.	Method and Structure of MEMS WLCSP Fabrication	9,540,232	01/10/2017
81.	Power Saving Method of Operating a Portable Computing Device	9,588,569	03/07/2017
82.	Single Point Offset Calibration for Inertial Sensors	9,594,095	03/14/2017
83.	MEMS-Based Proximity Sensor Device and Method	9,696,337	07/04/2017
84.	System Configured for Integrated Communication, MEMS, Processor, and Applications Using a Foundry Compatible Semiconductor Process	9,709,509	07/18/2017
85.	Method and Structure of MEMS PLCSP Fabrication	9,738,510	08/22/2017

No.	Description	Registration/ Application <u>Number</u>	Registration/ Application <u>Date</u>
86.	Method and Structure of MEMS PLCSP Fabrication	9,975,759	05/22/2018
87.	Selective Accelerometer Data Processing Methods and Apparatus	13/437,914	04/02/2012
88.	Methods and Apparatus for Mobile Device Power Management Using Accelerometer Data	13/759,027	02/04/2013
89.	Dynamic Temperature Calibration	13/940,199	07/11/2013
90.	Tower-Shaped Supporting Structure	14/233,903	01/21/2014
91.	System on a Chip Using Integrated MEMS and CMOS Devices	PCT US2010054567	10/28/2010

EXHIBIT C

Trademarks

No.	Description	Registration/ Serial Number	Registration/ Application Date
1.	SENSFIT	88/491,567	06/27/2019
2.	MCUBE (& design)	4,700,413	03/10/2015
3.	MCUBE	4,254,341	12/04/2012
4.	MCUBE	4,659,788	12/23/2014